Electrical, Optical, and Magnetic Properties of Magnetron-Sputtered and RTAed NiO:Nd Thin Films

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NiO has p-typesemiconducting property with bandgap of 3.6-4.0 eV [1], and it is cheap and environment-friendlywith excellent electrical and optical properties for various applications such as alkaline batteries, electrochemical capacitors, smart windows, and magnetic bar codes.NiO thin film has been prepared by several method; sol-gel process, spraypyrolysis, high temperature oxidation, pulse laser deposition, and magnetronsputtering [2]. In this study, NiO thin films were deposited using a NiO alloy target by radio frequency magnetron sputteringwhich has several advantages such as superior adhesion of thin films and easycontrol for deposition rate. Moreover, the 4f rare earth atoms, such as Nd, can have larger magnetic moment to enhance the ferromagnetism by incorporating metal oxide matrixin semiconductors [3]. The NiO thin films were doped with

various concentrations of Nd<sup>3+</sup> ions by co-sputteringmethod. The precursors with variousconcentration of Nd were annealed by rapid thermalannealing (RTA) to control the properties of the NiO:Nd thin films. Structural and morphological properties of the thin films were analyzed by using X-ray diffraction and atomic forcemicroscope. Optical and electrical characteristics of the thin films wereanalyzed by using an UV-Visible spectrophotometer and a Hall effect measurementsystem. Electrochemical capacitive behavior of the thin films was determined by using a potentiostat. The magnetic properties NiO:Nd thin films were analyzed by vibrating sample magnetometer.

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